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PATENT APPLICATION

**UNDER 37 CFR §1.116
EDITED PROCEDURE
ENTER ART UNIT 1792**

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

Group Art Unit: 1792

Application No.: 10/594,458

Examiner: L. VINH

Filed: September 26, 2006

Docket No.: 129546

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER

REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the September 15, 2008 Office Action, reconsideration of the rejection is respectfully requested in light of the following remarks.